

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Masahiko NAKAMORI, et al.  
Appl. No. : 10/536,621  
Filed : May 26, 2005  
For : POLISHING PAD AND METHOD  
OF PRODUCING  
SEMICONDUCTOR DEVICE  
Examiner : Sylvia McCarthur  
Group Art Unit : 1792

CERTIFICATE OF EFS WEB  
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February 28, 2008

(Date)



Katsuhiro Arai, Reg.43,315

AMENDMENT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action mailed December 10, 2007, please reconsider the present application in light of the following amendments and comments.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks/Arguments** begin on page 5 of this paper.